



Atty. Docket No.: A-69175-1/ MSS  
Client/Matter No.: 463035-650

3723-\$  
AF/61

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*In re* application of:

**Nam P. Suh et al.**

Serial No.: **10/029,158**

Filed: **December 21, 2001**

For: **APPARATUS AND METHOD FOR  
CHEMICAL MECHANICAL  
POLISHING OF SUBSTRATES**

Examiner: **RACHUBA, Maurina T.**

Art Unit: **3723**

San Francisco, CA 94111

Date: **September 13, 2004**

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**TECHNOLOGY CENTER 3700**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT/RESPONSE**

Sir:

In response to the Office Action mailed April 13, 2004, Applicants submit the following amendments and remarks accompanied by a Petition for Extension of Time under 37 CFR 1.136(a) with proper fees, extending the period for response by two (2) month.

**Amendments to the Specification** begin on page 2 of this paper

**Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper.

**Amendments to the Drawings** begin on page 10 of this paper.

**Remarks/Arguments** begin on page 11 of this paper.

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